This listing of claims will replace all prior versions and listings of claims in the application:

LISTING OF CLAIMS:

- 1. (Withdrawn) An optical head apparatus, comprising:
- a single monolithic semiconductor substrate having at least a first side and a second side; the first side including an air bearing surface;
- a laser integral with the first side having an emission facet substantially coplaner with the air bearing surface; and
 - a contact pad on the second side electrically bridged to the laser.
- 2. (Withdrawn) The optical head apparatus of claim 1, wherein the contact pad is electrically bridged to the laser by a conductive via extending from the laser around a corner of the substrate along the second side of the substrate connecting to the contact pad.
- 3. (Withdrawn) The optical head apparatus of claim 1 wherein the laser is defined by one of an oxidized and ion-implanted region.
- 4. (Withdrawn) The optical head apparatus of claim 1, further comprising a slider portion integral with the semiconductor substrate next to the air bearing surface wherein electrical connection to the contact pad does not interfere with aerodynamic operation of the slider portion.
- 5. (Withdrawn) The optical head apparatus of claim 4 wherein the contact pad on the second side is recessed with respect to the emission facet and the air bearing surface.

USSN: 10/711,527

Our Reference No.: ST 2626.04 US Art Unit: 2627

6. (Withdrawn) An apparatus comprising a single semiconductor substrate having a first region and a second region, the first region defining a slider, the slider including an air bearing surface, the second region defining a laser, the laser including a first contact and a second contact.

- 7. (Withdrawn) The apparatus of claim 6 wherein the first contact is a p-electrical contact and the second contact is an n-electrical contact.
- 8. (Withdrawn) The apparatus of claim 7 wherein the p-electrical contact is adjacent to a p-clad layer and proximate to an emission face, and an n-electrical contact adjacent to an n-clad layer.
- 9. (Withdrawn) The apparatus of claim 8 wherein the first and second contacts define a laser diode.
- 10. (Withdrawn) The apparatus of claim 6 wherein the second region comprises a vertical cavity surface emitting laser, the emitting laser having an emission facet which is substantially co-planar with the air bearing surface.
- 11. (Withdrawn) The apparatus of claim 10 wherein the second region is defined by an oxidized or ion-implanted region in a p-DBR mirror stack.
- 12. (Withdrawn) The apparatus of claim 7 wherein the p-electrical contact is recessed with the first and second regions.
- 13. (Original) An apparatus comprising a single monolithic device including an aerodynamic slider and at least one laser wherein the laser includes an aperture in an

USSN: 10/711,527

Our Reference No.: ST 2626.04 US

Art Unit: 2627

emission facet, the monolithic device being mounted on a read/write arms via a suspension mechanism, the device being used to read and write on an optical media.

- 14. (Original) The apparatus of claim 13 wherein a width "w" of the aperture is of smaller dimension than an output wavelength " λ " of the laser.
- 15. (Original) The apparatus of claim 14 wherein a reflective read/write surface of optical media during a read/write operation is positioned at an optical path-length "i" from the emission facet is less than the output wavelength " λ ".
- 16. (Original) The apparatus of claim 13 wherein the optical media comprises "phase change" media.
- 17. (Original) The apparatus of claim 16 wherein the "phase change" media comprises GeTeSb materials.
- 18. (Original) The apparatus of claim 17 wherein the media comprise a phase change layer positioned between a protective overcoat and a base or substrate.
- 19. (Original) The apparatus of claim 13 wherein the optical media comprises an outer overcoat of a diamond-like carbon or protective material, a first dielectric layer, a phase change layer, a second dielectric layer, a metal layer, a third dielectric layer, and a base or substrate.
- 20. (Original) The apparatus of 19 wherein the dielectric layers comprises ZnS:SiO₂.